

Search Notes

Application No.

10/605,326

Examiner

Stephen W. Smoot

Applicant(s)

YEH ET AL.

Art Unit

2813

SEARCHED

Class	Subclass	Date	Examiner
438	525	8/21/2004	SWS
438	528	8/21/2004	SWS
438	586	8/21/2004	SWS
438	592	8/21/2004	SWS
438	595	8/21/2004	SWS
438	637	8/21/2004	SWS
438	675	8/21/2004	SWS
438	766	8/21/2004	SWS
438	770	8/21/2004	SWS
Updated	Above	2/2/2005	SWS

*S.W.S.***INTERFERENCE SEARCHED**

Class	Subclass	Date	Examiner

**SEARCH NOTES
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR
Key Words: Ion Implantation - Tilt, Sidewall; Thermal Oxidation; Rapid Thermal Process;	8/21/2004	<i>S.W.S.</i> SWS
Self-Aligned Contact (SAC); Plug; Contact Opening, Contact Hole, Conductive Via; Gate, Source, Drain.	8/21/2004	<i>S.W.S.</i> SWS
Updated Above Search	2/2/2005	<i>S.W.S.</i> SWS
Implantation - Nitrogen, Oxygen, Argon; Field Effect Transistors.	2/2/2005	<i>S.W.S.</i> SWS
Search Tools - EAST (attached): USPAT; US PG PUBS; Derwent; EPO; JPO; IBM TDB	8/21/2004 <i>S</i> 2-2-05	SWS <i>S.W.S.</i>